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substrate support member, the shared aperture being in fluid communication with a rinsing solution source and an inhibitor source.

20. The apparatus of claim 19, wherein the shared aperture is configured to cooperatively dispense a rinsing solution and an inhibiting agent.

REMARKS

This is intended as a full and complete response to the Restriction Requirement dated September 24, 2002, having a shortened statutory period for response set to expire on October 24, 2002. Claims 1, 7 and 14 have been amended to correct minor grammatical inconsistencies. Restriction to one of the following inventions is required under 35 U.S.C. 121:

- I. Claims 1-13, drawn to a method of making a semiconductor device, classified in class 438, subclass 704.
- II. Claims 14-20, drawn to an apparatus, classified in class 257, subclass 678.

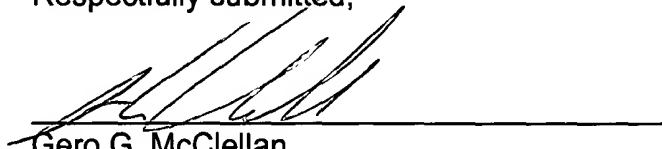
The Examiner states that the inventions of Group I and II are distinct because the apparatus as claimed can be used to practice another and materially different process such as one for forming package for semiconductor devices. Applicants elect claims 1-13, Group I, with traverse.

If the claims of Group II can be used to practice forming packages for semiconductor devices, as asserted by the Examiner, then the claims of Group I can also be used to practice the same. Specifically, claim 14 of Group II recites an apparatus for removing an edge bead from a substrate, and claim 7 of Group I recites a method for removing an edge bead from a substrate. (See preambles.) Claim 14 further recites means for dispensing an edge bead removal solution onto a substrate, means for rinsing a surface of the substrate, and means for applying an inhibitor to the surface

of the substrate. Likewise, claim 7 recites rinsing the substrate surface, applying an edge bead removal solution to the substrate surface; and rinsing the substrate surface to remove residue edge bead removal solution, wherein the rinsing includes applying an inhibitor solution to the substrate. Therefore, the Applicant believes that the basis for restriction is improper. Applicant respectfully requests that the restriction be withdrawn or that the Examiner elaborate on, and substantiate, the basis for the restriction.

Applicant respectfully requests withdrawal or modification of the restriction requirement to permit prosecution of claims 1-20.

Respectfully submitted,



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